Program

International Conference on

Semiconductor technology for ultra large scale integrated circuits and thin film transistors

July 7 - 12, 2013 Villard-de-Lans (Grenoble area), France

Conference Chair

Yue Kuo Texas A&M University, USA

Conference Co-Chairs

Gennadi Bersuker Sematech, USA

Cor Claeys IMEC, Belgium





Engineering Conferences International

32 Broadway, Suite 314 - New York, NY 10004, USA Phone: 1 - 212 - 514 - 6760, Fax: 1 - 212 - 514 - 6030 www.engconfintl.org – <u>info@engconfintl.org</u> Grand Hôtel de Paris 124, Place Pierre Chabert 38 250 Villard de Lans, France Tel +33 (0) 476-95-10-06 Engineering Conferences International (ECI) is a not-for-profit global engineering conferences program, originally established in 1962, that provides opportunities for the exploration of problems and issues of concern to engineers and scientists from many disciplines.

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Sunday, July 7, 2013

17:00 - 18:30	Conference check-in
18:30 - 19:30	Welcome reception
19:30 - 21:00	Dinner

NOTES

- Audiotaping, videotaping and photography of presentations are strictly prohibited.
- Please do not smoke at any conference functions.
- Turn your mobile phones to vibrate or off during technical sessions.
- Technical Sessions will be in the Village Conference Center.
- Meals and poster sessions/social hours will be in the hotel.
- Be sure to check your contact information on the Participant List in this program and make any corrections to your name/contact information online. A corrected copy will be sent to all participants after the conference.
- Speakers Please leave at least 5 minutes for questions and discussion. Be available for discussion during meals and social periods

Monday, July 8, 2013

07:00 - 08:30	Breakfast
08:45 - 08:55	Welcome and Introduction to the conference Yue Kuo, Conference Chair Norman Li, ECI Conference Liaison
	<u>Session 1: Plenary</u> Session Chair: Yue Kuo, Texas A&M University, USA
08:55 - 09:35	The future of heterogeneous and diversified ULSI nanoelectronics Simon Deleonibus, CEA-LETI, France
09:35 - 10:15	Post-SI CMOS technologies based on high-mobility channels Tso-Ping Ma, Yale University, USA
10:15 - 10:45	Coffee break
	<u>Session 2: Future devices</u> Session Chairs: Gennadi Bersuker, Sematech, USA Jin Jang, Kyung Hee University, Korea
10:45 - 11:15	Status and trends in GE CMOS technology Cor Claeys, Imec, Belgium
11:15 - 11:45	A possibility of application of crystalline indium-gallium-zinc-oxide to very large scale integration Shunpei Yamazaki, Semiconductor Energy Laboratory Co., Ltd., Japan
11:45 - 12:15	Printed organic TFTs on flexible substrate for CMOS circuits Micael Charbonneau, CEA Liten-17, France
12:30 - 13:30	Lunch
13:45 - 14:15	Monolayer diamond FETs consist of fluorinated graphene channel Mutsuko Hatano, Tokyo Institute of Technology, Japan
14:15 -14:35	Comparison of organic pulse-generator circuits for ferroelectric memories fabricated by all-additive printing David E. Schwartz, PARC, USA
14:45 - 19:30	Ad hoc sessions / free time for discussions
19:30 - 20:00	Dinner
20:00 - 21:30	Poster Session and social hour

Tuesday, July 9, 2013

07:00 - 08:30	Breakfast
	<u>Session 3: 3D and new devices</u> Session Chairs: Junichi Murota, Tohoku University, Japan Arokia Nathan, Cambridge University, United Kingdom
08:45 - 09:15	Crystalline nanowires for 3D VLSI applications Thomas Ernst, CEA-LETI, France
09:15 - 09:45	Silicon on thin buried oxide (SOTB) technology for ultralow-power (ULP) applications Nobuyuki Sugii, Low-power Electronics Association & Project, Japan
09:45 - 10:15	Towards higher integration thin film technology by involving P-type and N-type vertical channel thin film transistor Olivier Bonnaud, IETR University of Rennes, France
10:15 - 10:45	Coffee break
10:45 - 11:15	Innovative sharp switching devices Sorin Cristoloveanu, IMEP, France
11:15 - 11:45	Technology and design challenges in sub 30 nm DRAM Ewoud Vreugdenhil, ASML Netherlands B.V., The Netherlands
	<u>Session 4: Oxide TFTs</u> Session Chairs: Cor Claeys, IMEC, Belgium Guglielmo Fortunato, CNR-IMM, Italy
11:45 - 12:15	Novel integration process for IGZO MO-TFT fabrication on gen 8.5 PECVD and PVD systems - A quest to improve TFT stability and mobility Beom Soo Park, AKT, USA
12:15 - 12:45	Roles of hydrogen in amorphous oxide semiconductor Toshio Kamiya, Tokyo Institute of Technology, Japan
13:00 - 14:00	Lunch
14:15 - 14:45	Effect of electron density in channel on TFT performances in Dual Gate Oxide TFTs Jin Jang, Kyung Hee University, Korea
14:45 - 15:05	Conduction Band Lowering Effect in Crystalline Indium-Gallium-Zinc-Oxide Thin Film Transistors Daisuke Matsubayashi, Semiconductor Energy Laboratory Co., LTD., Japan
15:05 - 15:25	Trap densities in ZnO TFTs with SiN _x /SiO stacked gate insulators fabricated using several N ₂ O flow rate during SiO _x deposition Mutsumi Kimura, Ryukoku University, Japan
15:25 - 15:50	Coffee break
15:50 - 16:20	Amorphous semiconductor oxide TFTs and applications Arokia Nathan, University of Cambridge, United Kingdom

Tuesday, July 9, 2013 (continued)

16:20 - 16:50	Negative-bias with illumination stress induced state creation in amorphous IGZO thin-film transistor Mamoru Furuta, Kochi University of Technology, Japan
16:50 - 19:30	Ad hoc sessions / free time for discussions
19:30 - 21:00	Dinner
21:00 - 22:30	Panel: Challenges in Materials & Fabrication followed by social hour/discussions

Wednesday, July 10, 2013

07:00 - 08:30	Breakfast
	<u>Session 5: Gate dielectric and processes</u> Session Chairs: Shunpei Yamazaki, Semiconductor Energy Laboratory Co., Ltd., Japan John Rowlands, Thunder Bay Regional Research Institute, Canada
08:45 - 09:15	Gate dielectrics in CMOS and TFTs John Robertson, Cambridge University, United Kingdom
09:15 - 09:45	Defect generation caused by charge transfer in nano-layer oxides Gennadi Bersuker, SEMATECH, USA
09:45 - 10:15	Structure and electronic properties of polycrystalline dielectrics Keith McKenna, University of York, United Kingdom
10:15 - 10:45	Monolithic integration of oxides on semiconductors Alex Demkov, University of Texas, USA
10:45 - 11:15	Coffee break
	<u>Session 6: Other TFTs</u> Session chairs: Tso-Ping Ma, Yale University, USA Shinichi Takagi, The University of Tokyo, Japan
11:15 - 11:45	Contact effects in organic and inorganic thin film transistors Guglielmo Fortunato, IMM-CNR, Italy
11:45 - 12:15	Flexible single-grain Si TFTs on a plastic substrate Ryoichi Ishihara, Delft University of Technology, The Netherlands
12:15 - 12:35	Characterization of undoped/doped zinc oxide films by sol gel method on different substrates Sonik Bhatia, Kanya Maha Vidyalaya, Jalandhar, India
13:00 - 14:00	Lunch
14:00 - 20:00	Excursion / free time for discussions
20:00 - 21:30	Dinner
21:30 - 22:30	Panel: Challenge in Applications followed by social hour and discussion

Thursday, July 11, 2013

07:00 - 08:30	Breakfast
	<u>Session 7: LEDs & Group IV Materials and Devices</u> Session Chairs: Olivier Bonnaud, University of Rennes 1, France Nobuyuki Sugii, The University of Tokyo, Japan
08:45 - 09:15	Metal oxide high-K thin films – from gate dielectrics to nonvolatile memories to LEDs Yue Kuo, Texas A&M University, USA
09:15 - 09:45	Deep ultraviolet light emitting diodes Michael Shur, Rensselaer Polytechnic Institute, USA
09:45 - 10:15	Monolithic GE optical emitters for photonic-electronic integration Katsuya Oda, Hitachi, Ltd., Japan
10:15 - 10:45	Coffee break
10:45 - 11:15	III-V/Ge MOS transistor technologies for future ULSI Shinichi Takagi, The University of Tokyo, Japan
11:15 - 11:45	Atomically controlled CVD processing of group IV semiconductors for strain engineering and doping in ultralarge scale integration Junichi Murota, Tohoku University, Japan
	<u>Session 8: TFT imagers and others</u> Session chairs: Michael Shur, Rensselaer Polytechnic Institute, USA Sorin Cristoloveanu, IMEP-LAHC, France
11:45 - 12:15	Towards a digital radiology roadmap John A. Rowlands, Thunder Bay Regional Research Institute, Canada
12:15 - 12:45	Flat-panel X-ray image sensor using thin film transistors and field emitter arrays Wei Zhao, SUNY at Stony Brook, USA
13:00 - 14:00	Lunch
14:15 - 14:45	Wafer-scale CMOS imager technology Nigel M. Allinson, ISDI Ltd., United Kingdom
14:45 - 15:05	Nanocrystalline silicon thin film transistors for neuromorphic applications Eric M. Vogel, Georgia Institute of Technology, USA
15:05 - 19:30	Ad hoc discussions / free time for discussions
19:30 - 21:30	Banquet
21:30 - 22:30	Social hour / Free discussions

Friday, July 12, 2013

07:00 - 09:00 Breakfast

Departures

Poster List

- 1. Polychromatic single-shot spectroscopy on SOI-FET trapped electrons Jaime Tenorio-Pearl, Cambridge University, United Kingdom
- 2. High mobility IGZO TFT fabricated by solution-based non-vacuum mist chemical vapor deposition Mamoru Furuta, Kochi University of Technology, Japan
- **3. Electrical detection of trapped charges using an ultra-thin SOI-FET** Stephen Fleming, University of Cambridge, United Kingdom
- 4. Temperature dependences of transistor characteristics of SD and LDD POLY-SI TFTS Mutsumi Kimura, Ryukoku University, Japan
- 5. Novel application of crystalline indium-gallium-zinc-oxide technology to LSI: Dynamically reconfigurable programmable logic device based on multi-context architecture Yuki Okamoto, Semiconductor Energy Laboratory Co., Ltd., Japan
- 6. Multi-bit Unified Memory Concept in FinFETs with ONO Buried Insulator Sorin Cristoloveanu, IMEP-LAHC, France
- 7. Electrical characterization of ultrathin silicon-on-insultaro substrates static and split CV measurements in the pseudo-MOSFET Luca Pirro, IMEP-LAHC, France
- 8. Reliability evaluation and characterization of FDSOI ultra-thin buried oxides Guillaume Besnard, SOITEC, France
- 9. Unusual short-channel effects in SOI MOSFETs Carlos Navarro Moral, IMEP-LAHC, France
- **10. An Improved Semi-Classical Model to Investigate Tunnel-FET performance** Alberto Revelant, Universita Degli Studi Di Udine, Italy
- **11. Etch stop and sacrificial layers materials for 3D co-integration between NEMS and CMOS** Julien Philippe, CEA LETI, France